Structure fabrication for CLIC

CLIC08, Oct. 14-17, 2008 KEK, T. Higo

Strategy of structure fabrication at KEK

- Re-establish GLC/NLC structure fab technique – 60-100MV/m
- Extend it to heavily damped structure for CLIC
 Disk damp confirmation
- Learn about fabrication by all milling
 - Study high gradient performance
 - Study mass production feasibility
- Discuss about the practical candidate
 - For near future application in a few years

Structure fabrication plan

			作業工程表 X-BAN				
			日付範囲 2008/09/11~2009/11/06			月 5月 6月 7月 8月	
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と機(4本分)		<u>+</u>	- ASSEMBLY				
粗加工 (u-corp)			Pre assembly & RF test				
住上げ加工(u-corp)			Bonding Tuning Baking (SLAC)				
計測GREKO			Installation for Nextef area	å i i i i i i i i i i i i i i i i i i i			
ACUUM CHAMBER			— High power test				
設計&区面作成					C10, CD10		
			C10_vg1.35 #3,#4		+++++++++++++++++++++++++++++++++++++++		
製作&評価			- 加工&計測				
F計測ジグ			Bonding Tuning Baking (SLAC)				
設計&図面作成			High power test				
製作を評価			CD10_vg1. 35 #1, #2				
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設計&図面製作			加工&計測 Bonding Tuning Baking (SLAC)				
製作&評価			High power test				
SSEMBLY							
Pre Assembly&RF Test							
洗浄							
Final Assembly							
Installation for Nextef area							
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Disk-damp fabrication

- Started with technology of T18_VG2.4_Disk
 - Material
 - OFC
 - Machining
 - Usual turning for disk
 - Usual milling for coupler of mode converter type
 - Surface treatments
 - SLAC does all
 - CP, DB and VAC baking
- Take the same method but with milling in each cell
 - Mechanical design by KEK
 - Fabrication study done

TD18_VG2.4_Disk Fabrication test





Most concerns are Dimension Flatness

Cell #1

Cell #19

Flatness

Flatness better than 1.5micron in free position

We estimate that the flatness becomes better <1 micron when pushed onto the flat surface.

Flatness if OK.



We found recently the difficulty in dimension control

•Different measurement results between vendor and KEK about ~20microns!

Vendor suffers from big burrs at the top

The creation of burr itself should be suppressed!

→ improve finish turning. Study in progress.
 If it is not realized by vendor, KEK should do final cut.
 The re-scheduling become needed.

- •Slanted wall for waveguide channel and cell wall by several microns / several mm depth. Too much!! We are under investigation of improvement.
- •We wait for the confirmation of the reasonable precision It should be within several microns

•C10 and CD10 follow the fabrication of Disk-damp

Quad fabrication and test

- Present mission
 - Fabrication with all ball point milling
 - Assembly for high power realization
 - Non heat treated cavity in a vacuum vessel
- Discussions to be made
 - Feasibility for near future LC
 - Pros and cons in general
 - Precision alignment issue comes after high power

Status of four quadrants

- Brushed up the machining technique
 - Longitudinal: a few microns / 200mm
 - We think this controllability necessary to assure the precision of the overall 3D surface creation
 - Transverse direction: within ± a few microns
- Now we decided to make the actual four quadrants
 - Four will be delivered to KEK by mid Nov.

Dimensions to be confirmed

Longitudinal position

Flatness





Depth of cell surface (a, b)



Reference surface flatness



A Flatness: 4 µm

- B Flatness: $3 \mu m$, Perpendicularity w.r.t. A: $4 \mu m$
- C Perpendicularity w.r.t. A+B: 2 μ m

Measurement was performed by vendor. KEK measurement is consistent.

Longitudinal dimension control



Profile of test cut quadrant Q1-0

Measured w.r.t. A-B-C reference planes.

Green lines are ±2.5 microns.

KUM data = NWDSQ7.csv



Milled surface view

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50 micron rounding

Reference plane formation by milling

Cavity wall formation



Tuning sensitivity and requirement

- Cavity sensitivity by Riccardo
 - df/db=–1MHz/micron
 - df/da=+0.24MHz/micron
 - d f /dgap (gap between quads) = +0.37MHz/micron
- Tuning sensitivity
 - Riccardo: +10MHz/0.3mm-push, -10MHz/0.4mm-push-back
 - Higo: cone, height h, base r=4.2/2:
 - df/dh=+12MHz/mm
- Tuning amount
 - Riccardo requirement form RF match: ±5MHz
 - Vendor potential $\sim \pm 5 \mu m \rightarrow \pm 5 MHz$
 - Required tuning amount $<\pm 10$ MHz $\rightarrow 0.5$ mm/hole
 - Fab. At 20C and operation at 30C \rightarrow 2MHz
 - Temperature tuning capability $\pm 10C \rightarrow \pm 2MHz$

Rough test results of dimpling for rf tuning 081003 Y.Higashi

Dimpled height

0.43mm+/- 50µm 0.63mm+/- 50µm

Not big torque was applied -> standard torque for M5 bolt

@ Deterioration of flatness, straightness and twist of structure due to dimple tuning should be considered.

Vacuum chamber preparation



- •Quads are assembled and fixed to upper big flange.
- •CF114 flange equipped with waveguide flange feature.
- •Adjustment of electric phase and position might be difficult. We may introduce bellows to CF114?
- Gaskets with different thicknesses are prepared for adjustment.
 VCR connector for copper cooling tube with EBW to quad body.
 Vacuum sealing by U-tight seal, similar to helicoflex but cheap.
 Chamber is EB finish. Baking or pot22
- •Chamber is EP finish. Baking or not??

Summary

- Disk-undamp fabrication #3, #4 in progress at SLAC.
- Disk-damp test cell inspected and some improvement was found necessary before actual fabrication all by vendor.
- Quad actual fabrication in in progress, and vacuum chamber fabrication also started.